

# Recycler flying wire profile analysis

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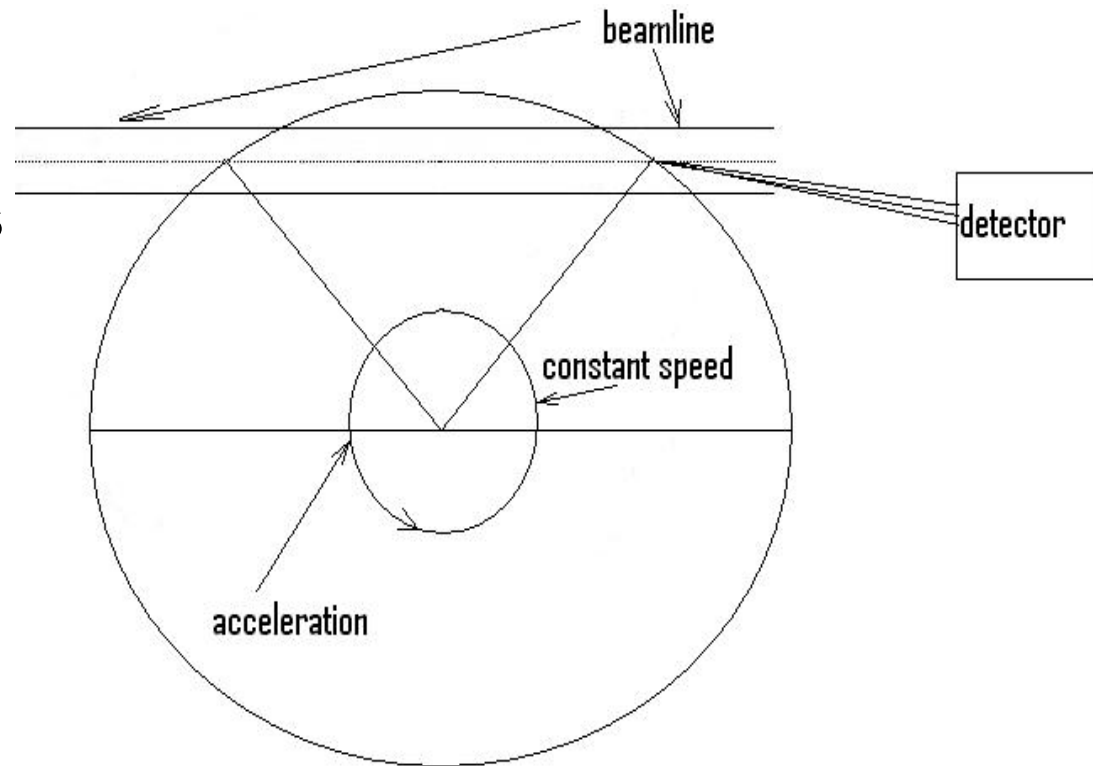
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# Purpose of work

- To develop a new method of beam profile measurement, based on flying wire data
- To apply this method for beam profile measurement, during electron cooling

# Flying wire profile measurement

- Fork length 133 mm
- $5\ \mu\text{m}$  carbon wire
- Nominal speed 6 m/s
- 16384 steps per 360 degrees,  $50\ \mu\text{m}$  per step
- Goes  $3/2$  turn:
  - $1/2$  acceleration
  - $1/2$  constant speed  
(goes 2 times through the beam)
  - $1/2$  deceleration



# Formulas, used in analysis

Initial fitting formula

$$f_1(x) = a \cdot \exp\left(-\frac{(x-b)^2}{2 \cdot \sigma^2}\right)$$

Formula, used for fitting in my work

$$f_2(x) = a_1 \cdot \exp\left(-\frac{(x-b)^2}{2 \cdot (\sigma_1)^2}\right) + a_2 \cdot \exp\left(-\frac{(x-b)^2}{2 \cdot (\sigma_2)^2}\right)$$

Criterion of fitting

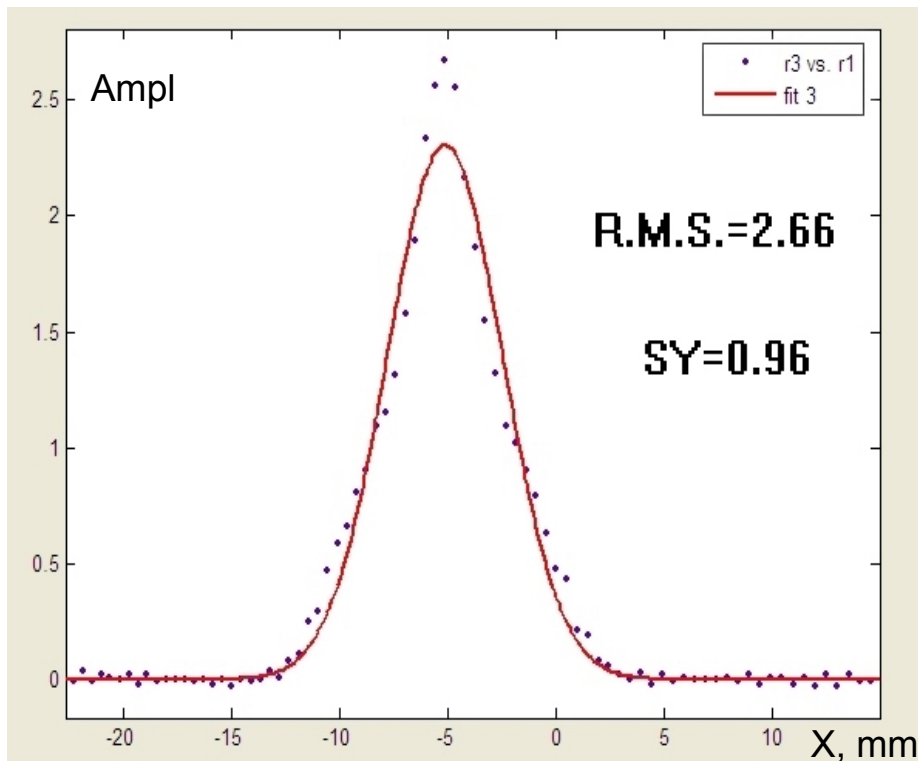
$$SY = \sum_i (f(x_i) - y_i)^2, \text{ we need to minimize SY for best fit}$$

Useful coefficients

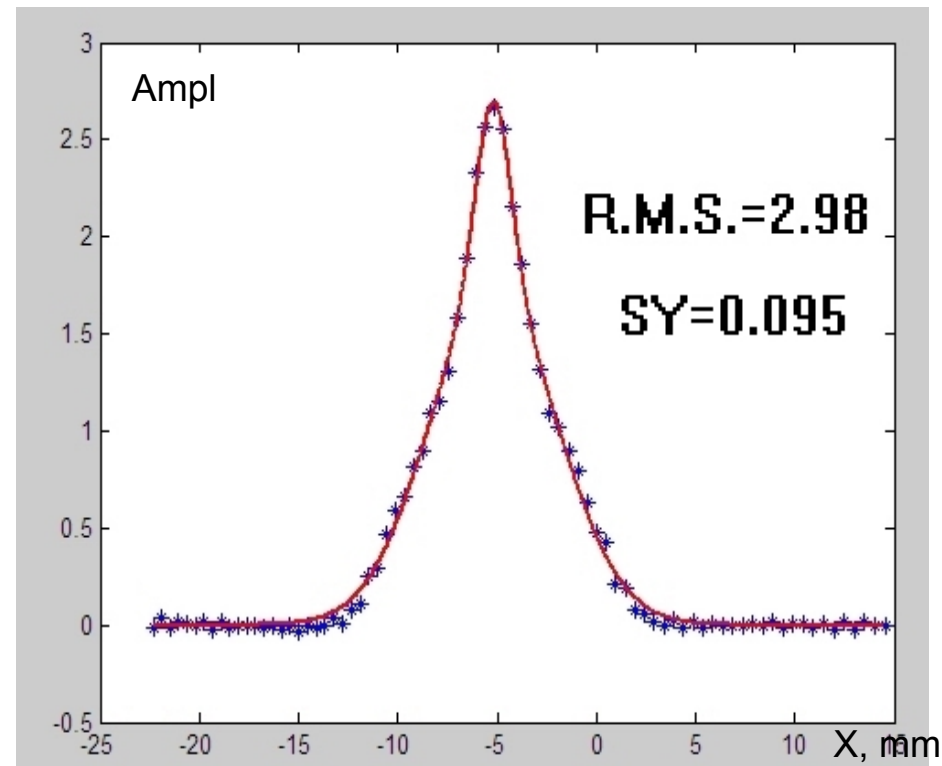
$$k = a_1 / a_2 \quad k_1 = \sigma_1 / \sigma_2$$

# Fitting of profile by one and two Gaussians

Fitting of profile by one Gaussian



Fitting of profile by two Gaussians

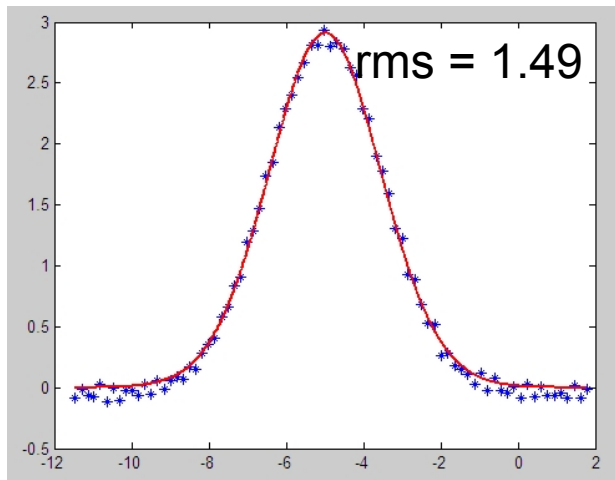
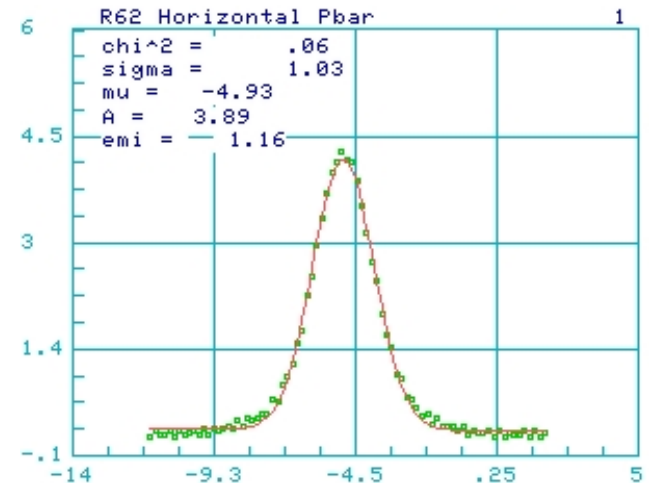
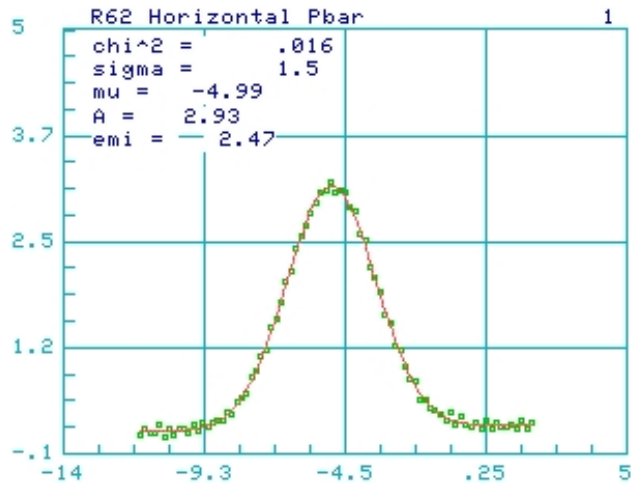


Stochastic and electron cooling was on for this measurement

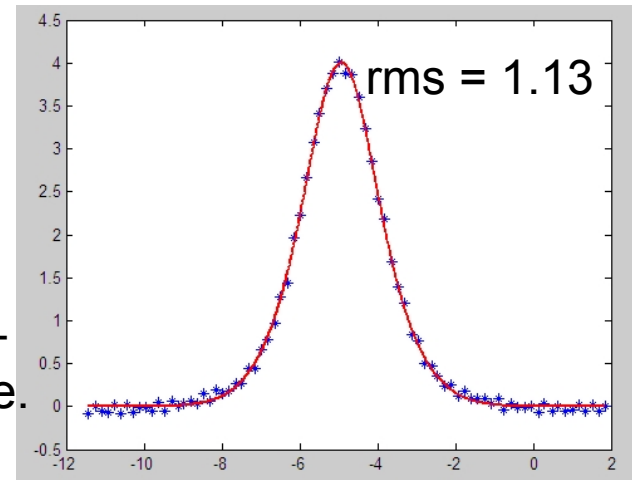
# Conditions of study

- 134 E10 pbars, 6.5  $\mu$ sec bunch
- Electron beam 100 mA
- Electron beam on-axis with pbars
- Good pbars lifetime
- Stochastic cooling is off

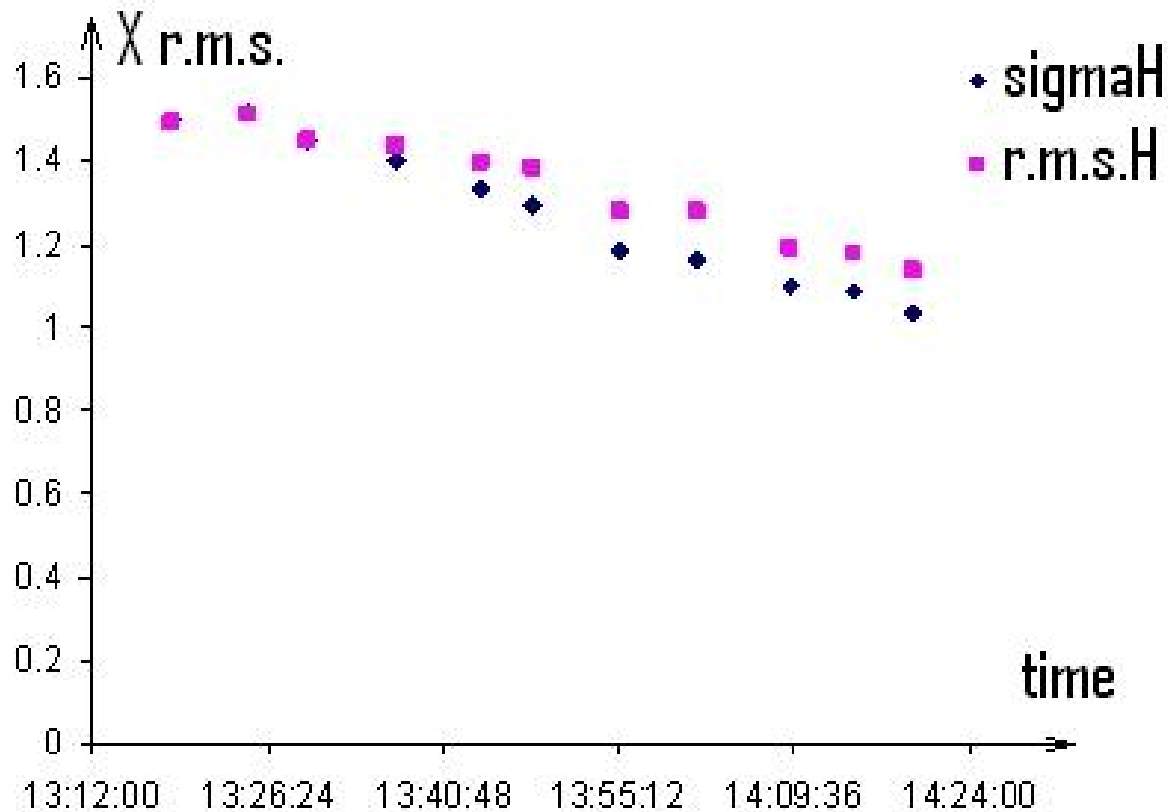
# First and last profiles of the study



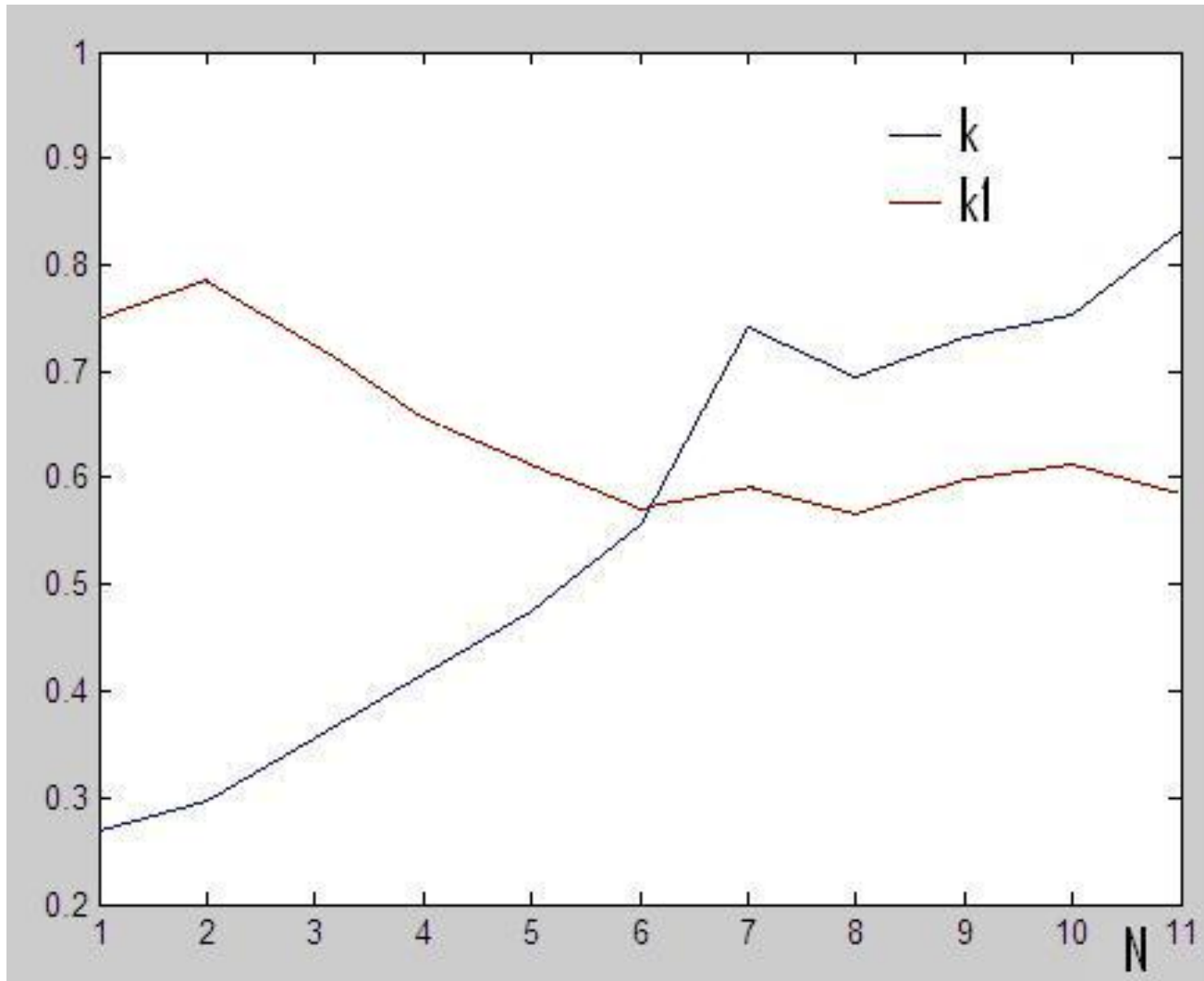
Fitting curve  
is the sum of  
two gaussians;  
the r.m.s. is  
calculated from  
the background-  
subtracted curve.



# Reduction in transverse beam size, $\sigma$ vs. r.m.s. based on two-Gaussian fit



# Ratio between amplitudes and r.m.s. of first and second Gaussians, during electron cooling



$$k = a_1 / a_2$$

$$k_1 = \sigma_1 / \sigma_2$$

# Conclusion

- The new method of beam profile measurement was developed. As a result of using this method, fitting errors decreased. This allows to calculate beam profile more precisely.
- New method was applied during electron cooling measurements